

Supplementary Information

Artificial 2D van der Waals Synapse Devices via Interfacial Engineering for Neuromorphic Systems

Woojin Park¹, Hye Yeon Jang¹, Jae Hyeon Nam¹, Jung-Dae Kwon² and Byungjin Cho^{1*}, Yonghun Kim^{2*}

¹ Department of Advanced Material Engineering, Chungbuk National University, Chungdae-ro 1, Seowon-Gu, Cheongju, Chungbuk, 28644, Republic of Korea; wjpark@chungbuk.ac.kr (W.P.); hyjang0581@gmail.com (H.Y.J.); jhnam0714@gmail.com (J.N.); bjcho@chungbuk.ac.kr (B.C.)

² Materials Center for Energy Convergence, Surface Technology Division, Korea Institute of Materials Science (KIMS), 797 Changwondaero, Sungsan-gu, Changwon, Gyeongnam, 51508, Republic of Korea; jdkwon@kims.re.kr (J.D.K.); kyhun09@kims.re.kr (Y.K.)

* Co-correspondence: bjcho@chungbuk.ac.kr (B.C.); Tel.: +82-(0)43-261-2417, kyhun09@kims.re.kr (Y.K.); Tel.: +82-(0)55-280-3281 Received: date; Accepted: date; Published: date

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1. Raman spectrum of WSe₂ and NbSe₂ after transfer process

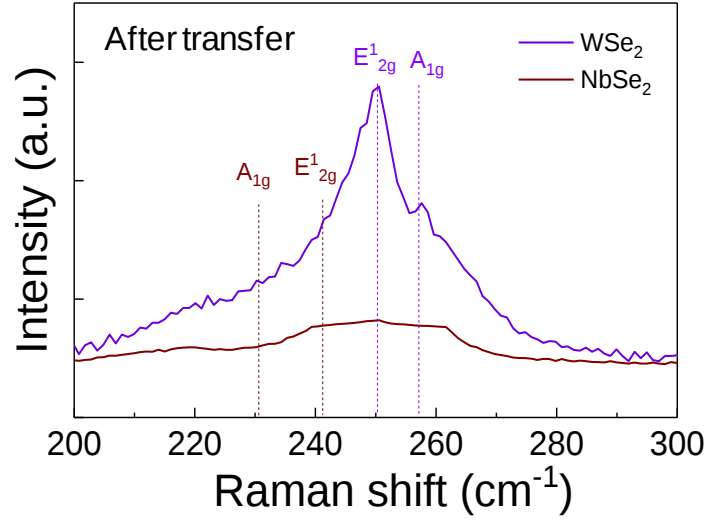


Figure S1. Raman spectrum of WSe₂ and NbSe₂ with stacked device structure after transfer process

2. Repeatability test of DC transfer double sweep curves with different Nb₂O₅ thicknesses

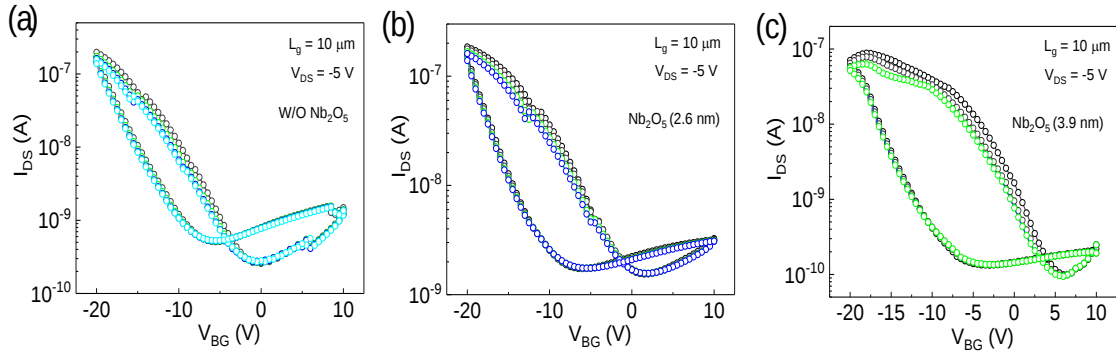


Figure S2. Repeating test of DC transfer curves with different Nb₂O₅ thicknesses

3. The dependence of DC sweep speed on transfer curves

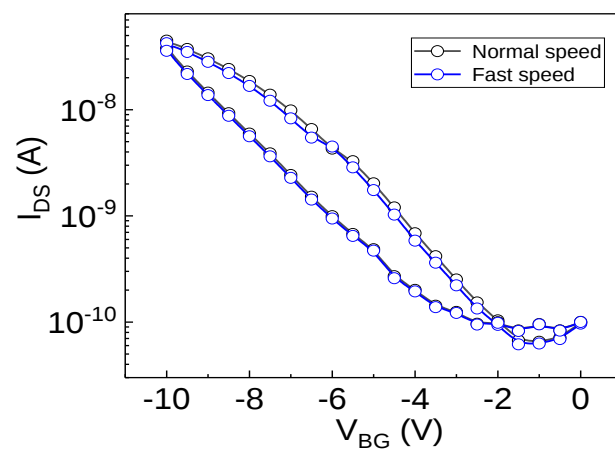


Figure S3. The dependence of DC sweep speed on transfer curves with 2.6 nm thickness of Nb_2O_5